

3D Simulations of Interacting Gliding Dislocation in 3C-SiC(001)

Steven Ceron,^{1,2} Hiroyuki Nagasawa,³ and Maki Suemitsu³

¹*Department of Mechanical Engineering, University of Florida, Gainesville, FL, USA*

²*NanoJapan: International Research Experience for Undergraduates Program, Rice University, Houston, TX., USA*

³*Research Institute for Electrical Communication, Tohoku University, Sendai, Japan*

3C-SiC has been identified as a leading semiconducting material for use in high, voltage, temperature, and frequency devices. In contrast to the other SiC polytypes, 3C-SiC has shown great potential through its high saturated electron drift velocity. The material also shows a very low density of states at the 3C-SiC/ SiO₂ interface making it an attractive option for use in power-switching MOSFETs. However, stacking faults form due to the 19.7% lattice mismatch at the 3C-SiC/ SiO₂ interface, and then expand throughout epitaxial growth, eventually terminating with other stacking faults, creating electrically active defects that lead to the electrical degradation of the material. After the epitaxial growth process has finished, the gliding of the partial dislocations at the edges of the stacking faults, instigated by the intrinsic shear stress of the system, begin to generate forest dislocations. The forest dislocations are created by the intersection of the counter pair of carbon-terminated stacking faults along the (-111) and (1-11) planes and the silicon-terminated stacking faults along the (111) and (-1-11) planes. By employing Monte Carlo simulations to model the generation of the dislocations we are able to analyze the density of forest dislocations throughout the system as a function of the shear stress, as well as a function of the temperature, material thickness, and stacking fault density. The results will allow for greater insight into the mechanisms by which leakage current density increases and how the generation of electrically active defects can be reduced through more sophisticated fabrication processes of 3C-SiC.

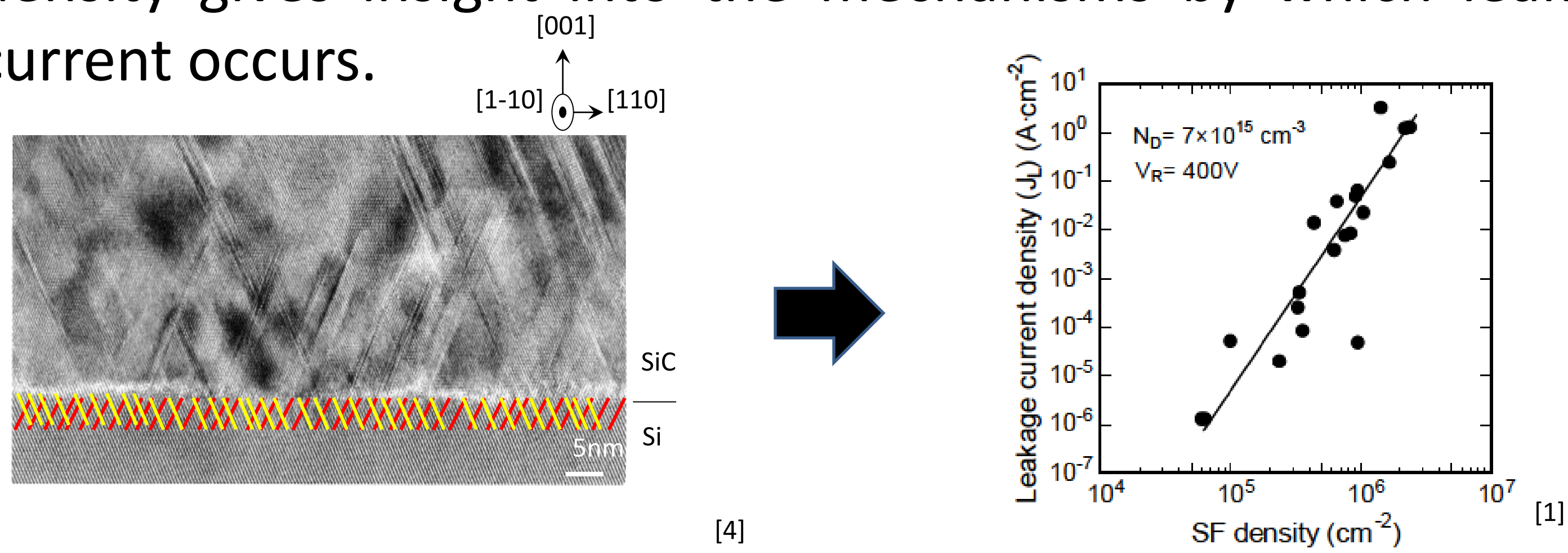
Interactions Between Gliding Dislocations in 3C-SiC (001)

Steven Ceron,^{1,2} Hiroyuki Nagasawa,³ and Maki Suemitsu³

¹University of Florida,²NanoJapan IREU,³Research Institute for Electrical Communication, Tohoku University

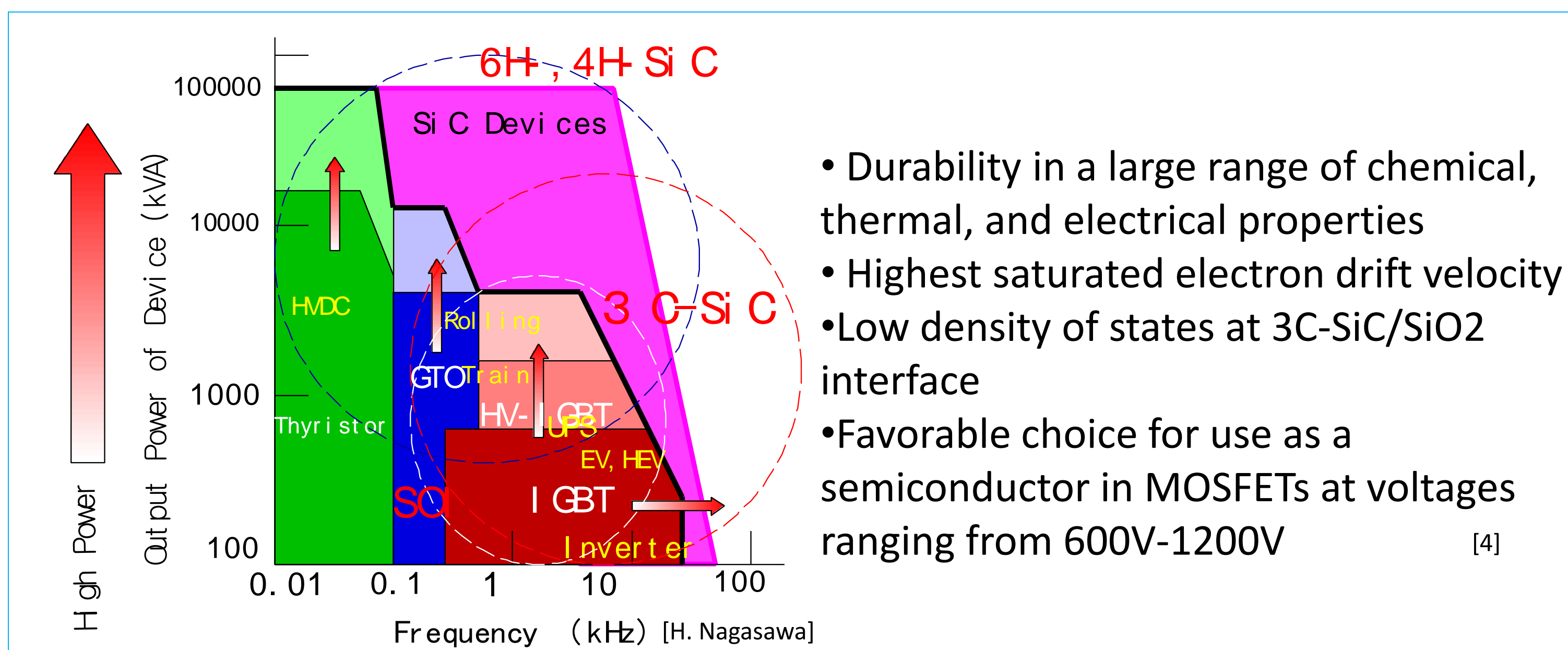
Motivation

3C-SiC is an attractive semiconducting material for use in a variety of high power electronic devices. The relationship between the forest dislocation (FD) and stacking fault (SF) density gives insight into the mechanisms by which leakage current occurs.



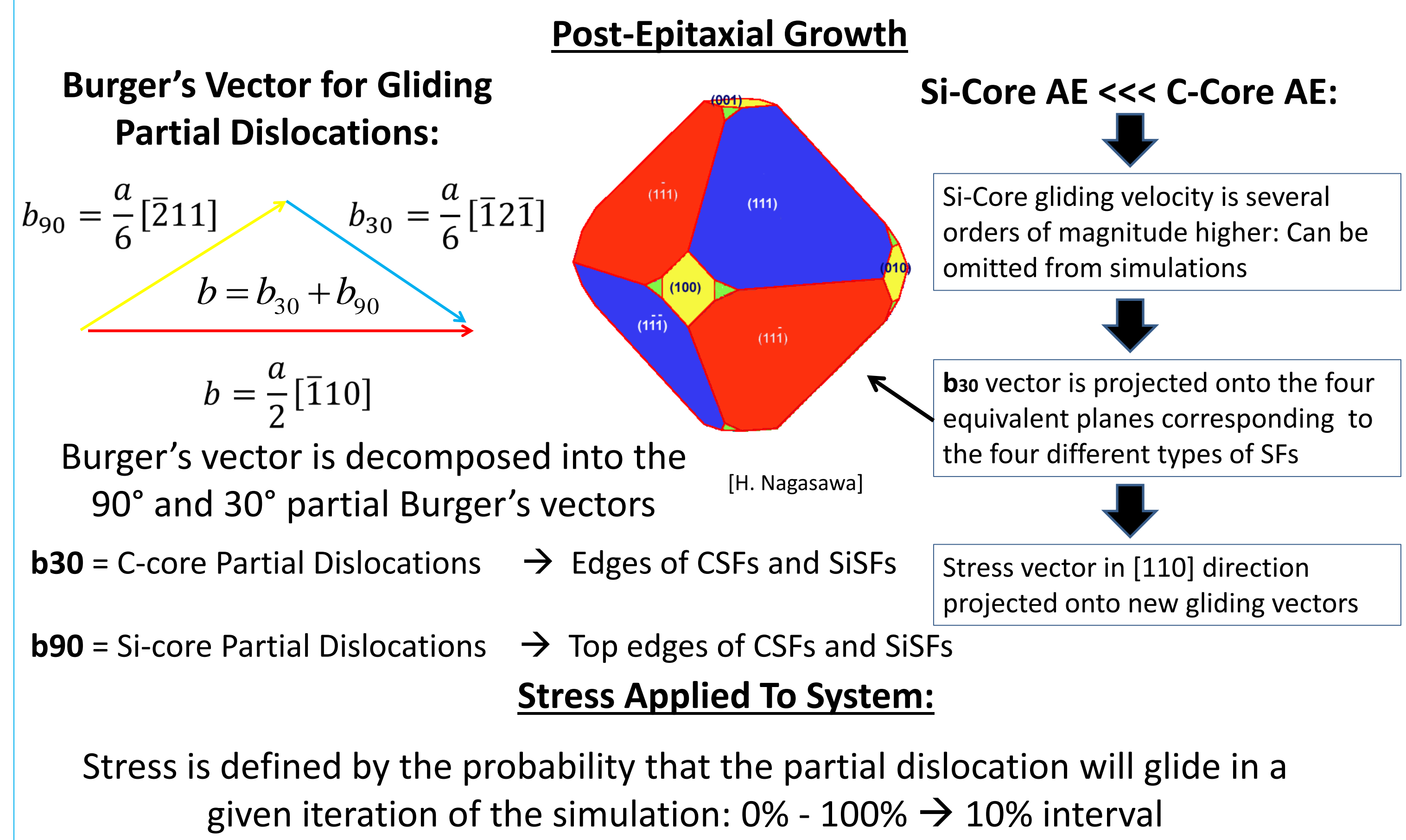
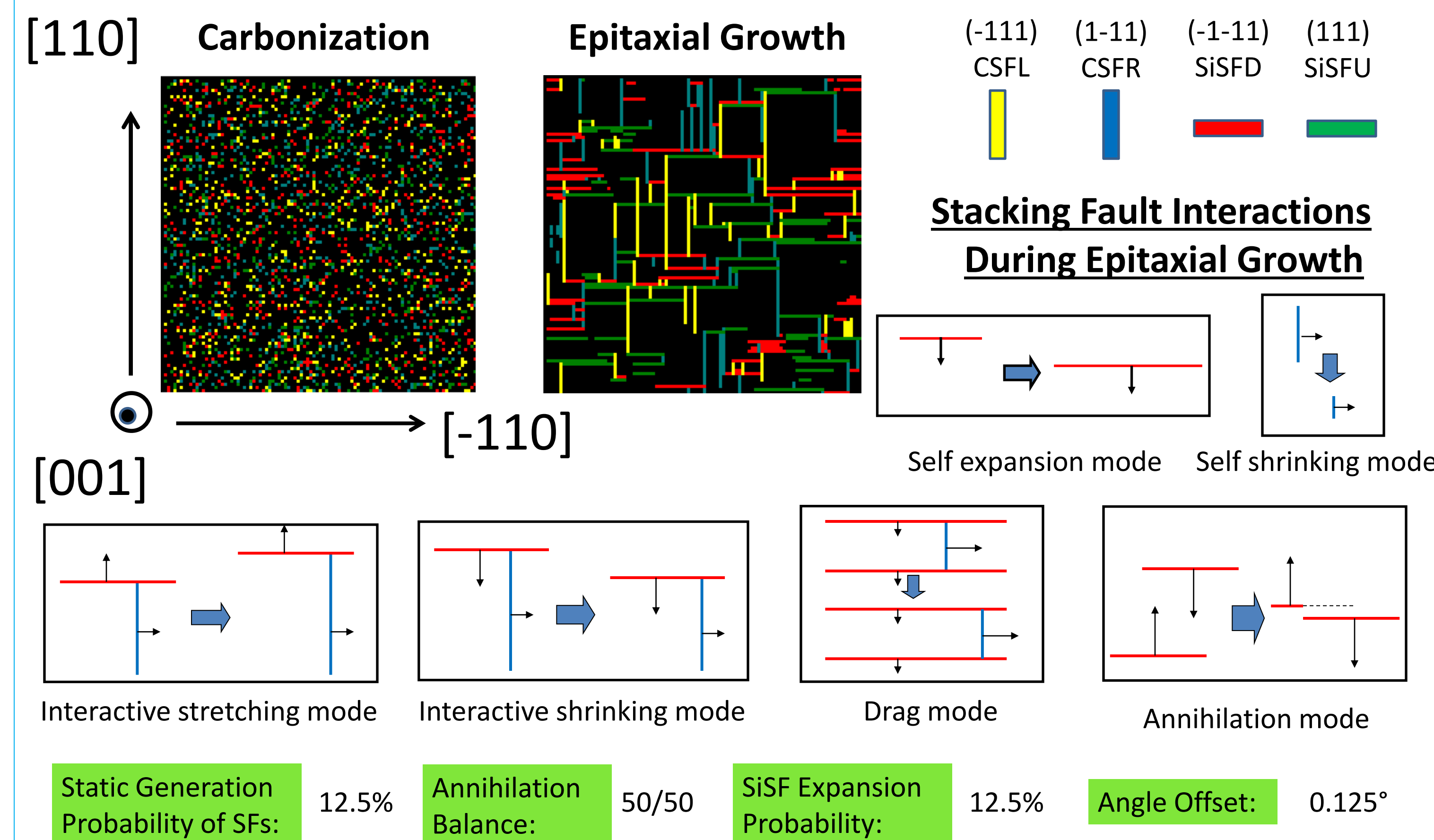
Goal: Analyze forest dislocation density as compared to the SF density in 3C-SiC (001).

Applications



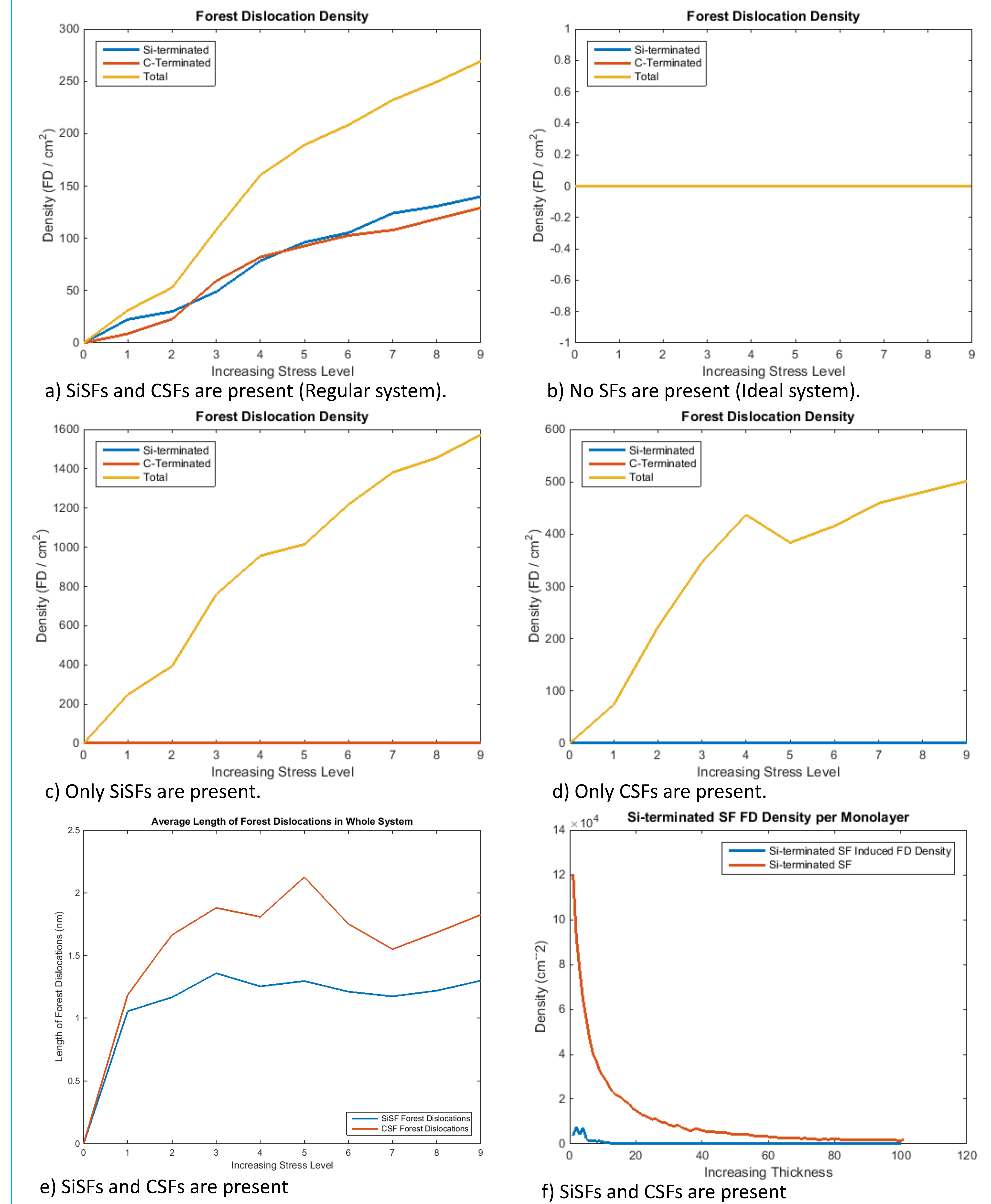
- Durability in a large range of chemical, thermal, and electrical properties
- Highest saturated electron drift velocity
- Low density of states at 3C-SiC/SiO2 interface
- Favorable choice for use as a semiconductor in MOSFETs at voltages ranging from 600V-1200V

3C-SiC (001) Monte Carlo Simulation Geometry



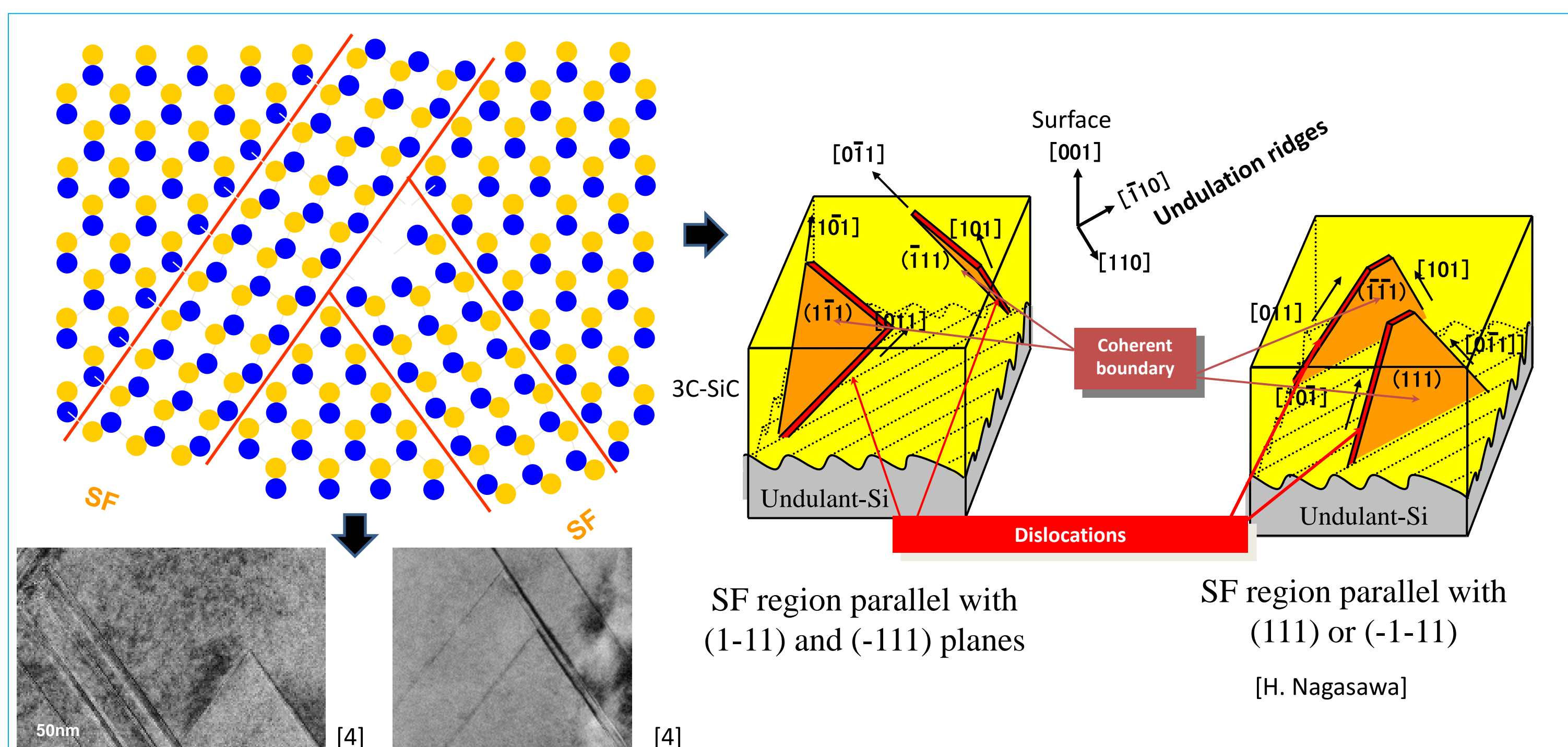
Stress is defined by the probability that the partial dislocation will glide in a given iteration of the simulation: 0% - 100% → 10% interval

Forest Dislocation and Stacking Fault Densities

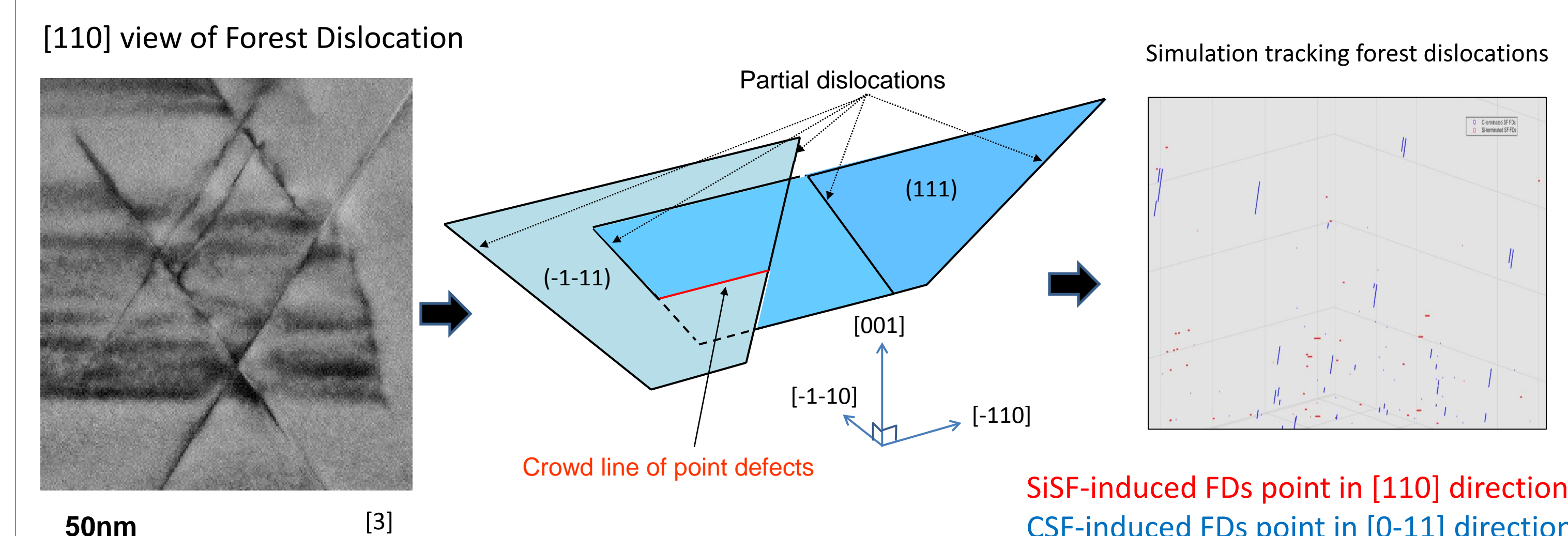


All data was obtained from simulations modeling a material of 30nm x 30 nm x 15nm in a length of 1000 time steps

Stacking Faults and Partial Dislocations



Forest Dislocations



Future Work

Define the activation energy of partial dislocations as a function of the temperature of the system and the area of the respective SF. Compare the simulation results to experimental results in order to have a clear insight into the mechanisms by which the generation of FDs affects the leakage current density.

1. Y. Sun, S. Izumi, S. Sakai, K. Yagi, H. Nagasawa, Computational Materials Science 79 (2013) 216-222.
2. T. Kawahara, N. Hatta, K. Yagi, H. Uchida, M. Kobayashi, M. Abe, H. Nagasawa, B. Zippelius, G. Pensl, Materials Science Forum Vols. 645-648 (2010) 339-342.
3. H. Nagasawa, R. Gurunathan, M. Suemitsu, Materials Science Forum Vols. 821-823 (2015) 108-114.
4. H. Nagasawa, M. Abe, K. Yagi, T. Kawahara, Silicon Carbide, Vol. 1: Growth, Defects, and Applications (2010) 95-113.